MICRON.100C1

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Primary Examiner Appl. No.

10/608,913

Applicant

Craig A. Hickman

Filed

June 26, 2003

For

DEVICE AND METHOD OF **CORRECTING EXPOSURE**

DEFECTS IN

PHOTOLITHOGRAPHY

Group Art Unit

2851

Examiner

Rodney Evan Fuller

Attny Docket No.:

MICRON.100C1

Customer No.

20,995

Confirmation No. 7050

CERTIFICATE OF FAX TRANSMISSION

I hereby certify that this correspondence and all marked attachments are being transmitted via facsimile to Examiner Rodney Evan Fuller, Fax No. 703-872-9306 of the USPTO on the date shown below:

July 22, 2004

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JUL 2 2 2004

AMENDMENT AND RESPONSE TO FINAL OFFICE ACTION

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 OFFICIAL

Dear Sir:

In response to the final Office Action of June 10, 2004, the Applicant submits the following amendment and remarks for consideration in connection with the above-captioned application.

Amendments to the Claims are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks/Arguments begin on page 7 of this paper.